

Attorney Docket: Serie 5444

Application No: Not yet assigned

Applicant: Christian DUSSARRAT, et al.

Examiner: Unknown

Filed: Herewith

TC/A.U: Unknown

Title: METHODS FOR PRODUCING SILICON NITRIDE FILMS AND
SILICON OXYNITRIDE FILMS BY THERMAL CHEMICAL
VAPOR DEPOSITION

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PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Prior to an examination of the merits of the above-identified U.S. patent application under 37 C.F.R. § 1.115, please first amend the application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims begin on page 3 of this paper.

Remarks begin on page 10 of this paper.